CLAIMS

1. An inlet nozzle assembly for an abatement apparatus for treating an effluent stream from a semiconductor processing tool, said inlet nozzle assembly comprising:

a delivery nozzle configured to deliver said effluent stream into an abatement chamber; and

a mount configured to couple with an enclosure defining said abatement chamber, said mount being further configured to receive said delivery nozzle for delivery of said effluent stream into said abatement chamber, wherein said mount comprises a downstream surface which couples with said enclosure defining said abatement chamber and an upstream surface from which said delivery nozzle extends; and wherein said delivery nozzle is configured to extend from said mount distal from said abatement chamber, wherein said delivery nozzle comprises;

an upstream inlet portion defining an inlet chamber for receiving said effluent stream;

a downstream delivery portion defining a delivery chamber for delivery of said effluent stream into said abatement chamber, wherein at least a part of said delivery portion is dimensioned to extend from said mount; and

a dividing plate defining an aperture which couples said inlet chamber with said delivery chamber; characterised in that said delivery nozzle is dimensioned to locate said dividing plate upstream of said upstream surface of said mount; said delivery nozzle further comprising an upstream body comprising said inlet portion and at least a part of said delivery portion and a downstream body comprising a remainder of said delivery portion, wherein said downstream body is dimensioned to extend from said upstream surface, through said mount and said enclosure to said abatement chamber.

2. The inlet nozzle assembly of claim 1, wherein said delivery nozzle is dimensioned to extend from a surface of said mount distal from said abatement chamber.

3. The inlet nozzle assembly of claim 2, wherein said delivery nozzle is dimensioned to upstand from said surface of said mount.

4. The inlet nozzle assembly according to any preceding claim, wherein at least a part of said delivery portion is dimensioned to upstand from said upstream surface.

5. The inlet nozzle assembly according to any preceding claim, wherein said mount is configured to receive at least a portion of a remainder of said delivery portion therewithin.

6. The inlet nozzle assembly according to any preceding claim, wherein said delivery portion is dimensioned to extend from upstream of said upstream surface to said abatement chamber.

7. The inlet nozzle assembly according to any preceding claim, wherein said upstream body is dimensioned to provide one of a plurality of different lengths of said at least a part of said delivery portion.

8. The inlet nozzle assembly according to any preceding claim, wherein said upstream body is dimensioned to provide a length of said delivery portion which delivers a selected flow profile of said effluent stream into said abatement chamber.

9. The inlet nozzle assembly according to any preceding claim, wherein said upstream body is dimensioned to provide a length of said delivery portion which avoids backflow of said effluent stream from said abatement chamber.

10. The inlet nozzle assembly according to any preceding claim, comprising a discontinuity shaped to separate said effluent stream into a least a pair of vortices and wherein said upstream body is dimensioned to provide a length of said

delivery portion which prevents said pair of vortices from extending into said abatement chamber.

11. The inlet nozzle assembly according to any preceding claim, wherein said upstream body is formed of material having at least one of a lower use temperature and a lower oxidation resistance than material forming said downstream body.

12. An abatement apparatus comprising at least one inlet nozzle assembly as claimed in any preceding claim.

13. The abatement apparatus of claim 12, comprising a plurality of said inlet nozzle assemblies, each having a having a different length.